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# **BSIM4.3.0 Model**

## **Enhancements and Improvements Relative to BSIM4.2.1**

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# OUTLINE

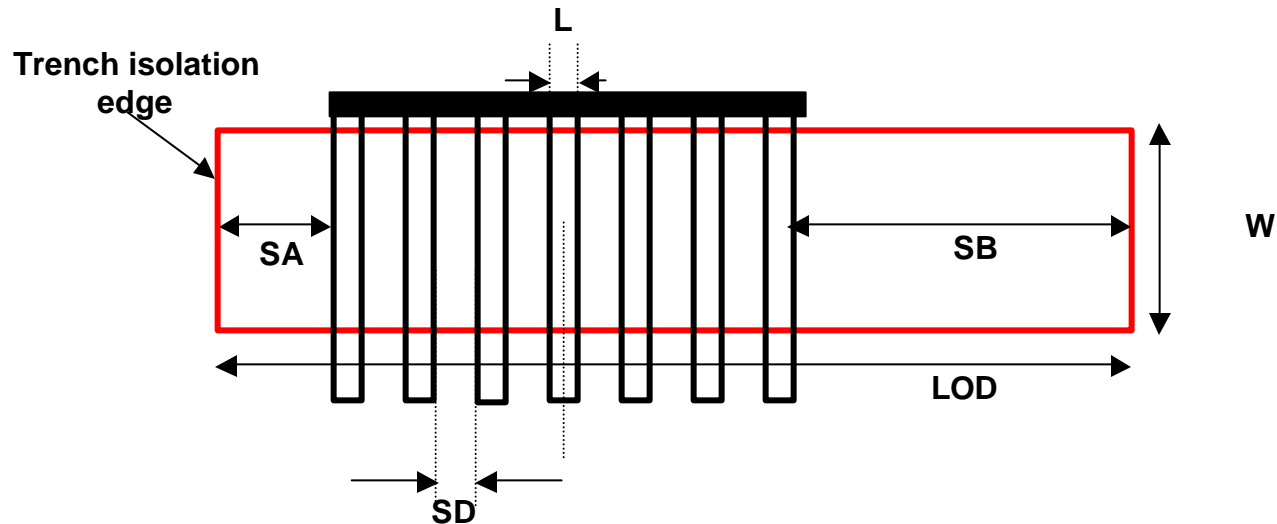
## New Features of BSIM4.3.0 beta' release

- ❖ Stress effect model
- ❖ New temperature model
- ❖ Holistic noise model enhancement
- ❖ Unified current saturation model
  - Velocity saturation
  - Velocity overshoot
  - Source injection thermal velocity limit
- ❖ New document for multi-layer gate tunneling
- ❖ Forward body bias



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## Model for Isolation-induced Stress Effects



Instance parameters added:  $SA$ ,  $SB$ ,  $SD$

$SD$  is neighbour finger distance which is constant throughout all the fingers.

**Stress effect calculation only if:** 1) both  $SA$  and  $SB$  are given and are larger than 0 for finger number  $NF=1$ ; 2)  $SA$ ,  $SB$  and  $SD$  are all given and are larger than 0 for  $NF > 1$

Intermediate geometry definitions :

$$LOD = SA + SB + NF \cdot L + (NF - 1) \cdot SD$$



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## Mobility Model With STI Stress

**Define :**

$$\begin{aligned} r_{m_{eff}} &= \Delta m_{eff} / m_{effo} = ( m_{eff} - m_{effo} ) / m_{effo} \\ &= \frac{m_{eff}}{m_{effo}} - 1 \quad (\text{relative mobility change due to stress}) \end{aligned}$$

So,  $\frac{m_{eff}}{m_{effo}} = 1 + r_{m_{eff}}$  (Vth insensitive to Lod, SA and/or SB)



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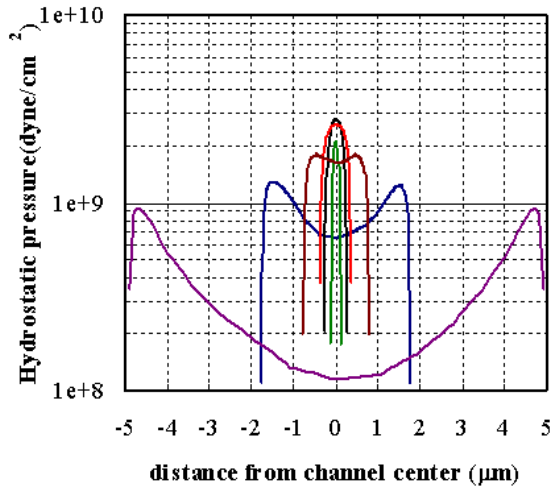
# Stress Effects Model-1/LOD Model

- ❖ Simple stress distribution function:  $1/(SA+L/2)$ ,  $1/(SB+L/2)$
- ❖  $r_{m_{eff}}$  expression with LOD, L, W, and T dependence

$$r_{m_{eff}} = \frac{ku0}{Kstress\_u0} \cdot (Inv\_sa + Inv\_sb)$$

$$Inv\_sa = \frac{1}{SA + 0.5 \cdot L_{drawn}} \quad Inv\_sb = \frac{1}{SB + 0.5 \cdot L_{drawn}}$$

$$Kstress\_u0 = \left( 1 + \frac{LKU0}{(L_{drawn} + XL)^{LLODKU0}} + \frac{WKU0}{(W_{drawn} + XW + WLOD)^{WLODKU0}} + \frac{PKU0}{(L_{drawn} + XL)^{LLODKU0} \cdot (W_{drawn} + XW + WLOD)^{WLODKU0}} \right) \times \left( 1 + TKU0 \cdot \left( \frac{Temperature}{TNOM} - 1 \right) \right)$$



- ❖ All data can be fitted well with only one set of parameters (ie. Global model for LOD effect) and do not need extra binning parameters if binning is desired.

- ❖ For multi-finger device:

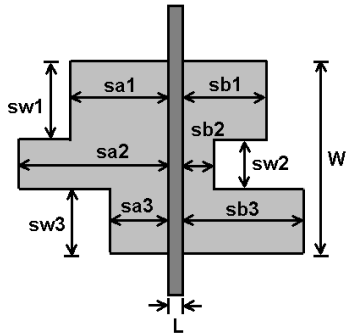
$$Inv\_sa = \frac{1}{NF} \sum_{i=0}^{NF-1} \frac{1}{SA + 0.5 \cdot L_{drawn} + i \cdot (SD + L_{drawn})}$$

$$Inv\_sb = \frac{1}{NF} \sum_{i=0}^{NF-1} \frac{1}{SB + 0.5 \cdot L_{drawn} + i \cdot (SD + L_{drawn})}$$

- ❖ For irregular LOD device:

$$\frac{1}{SA_{eff} + 0.5 \cdot L_{drawn}} = \sum_{i=1}^n \frac{SW_i}{W_{drawn}} \cdot \frac{1}{sa_i + 0.5 \cdot L_{drawn}}$$

$$\frac{1}{SB_{eff} + 0.5 \cdot L_{drawn}} = \sum_{i=1}^n \frac{SW_i}{W_{drawn}} \cdot \frac{1}{sb_i + 0.5 \cdot L_{drawn}}$$





## Stress Effect $m_{eff}$ , $u_{sat}$ Model

$$m_{eff} = \frac{1 + r_{meff}(SA, SB)}{1 + r_{meff}(SA_{ref}, SB_{ref})} m_{effo}$$

$$u_{sat} = \frac{1 + K \cdot r_{meff}(SA, SB)}{1 + K \cdot r_{meff}(SA_{ref}, SB_{ref})} u_{sato}$$

Where  $m_{effo}$ ,  $u_{sato}$  are low field mobility, saturation velocity at  $SA_{ref}$ ,  $SB_{ref}$



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## Stress Effect Model to $V_{TH0}$ , $K_2$ , $ETA_0$

$$K_{stress\_vth0} = 1 + \frac{LK_{VTH0}}{(L_{drawn} + XL)^{LLODKVTH}} + \frac{WK_{VTH0}}{(W_{drawn} + XW + WLOD)^{WLODKVTH}} + \frac{PK_{VTH0}}{(L_{drawn} + XL)^{LLODKVTH} \cdot (W_{drawn} + XW + WLOD)^{WLODKVTH}}$$

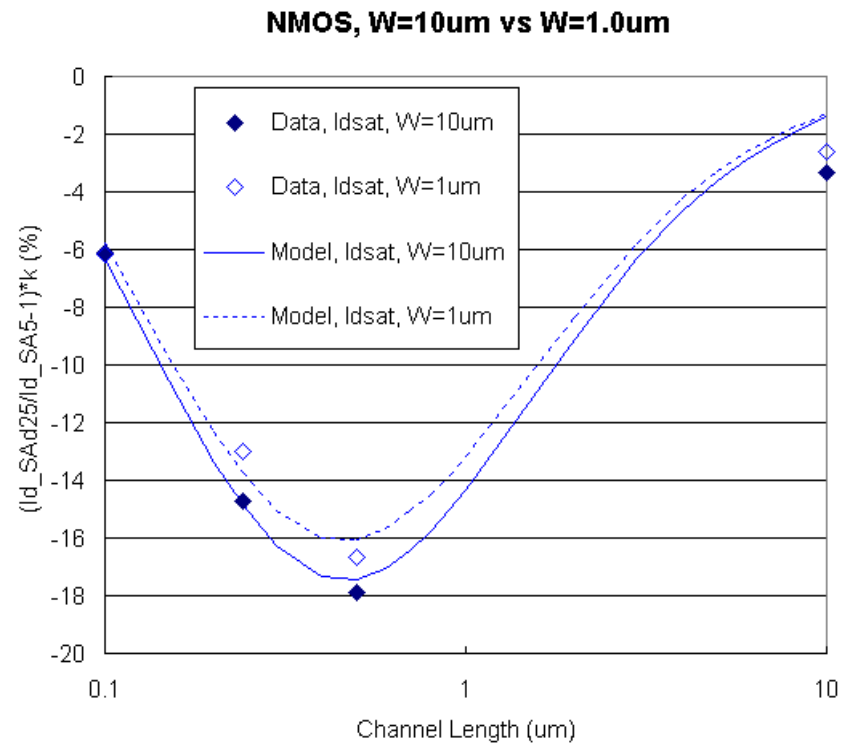
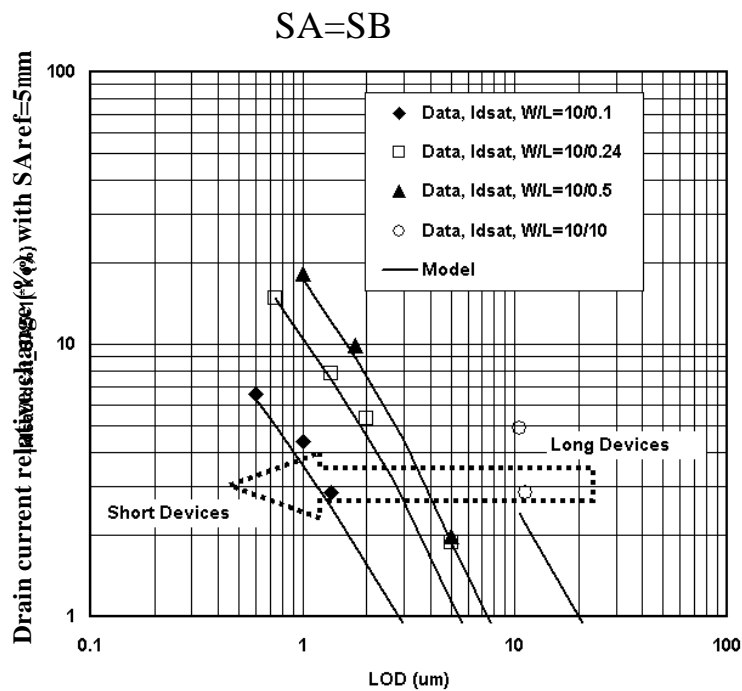
$$V_{TH0} = V_{TH0_{original}} + \frac{KV_{TH0}}{K_{stress\_vth0}} \cdot (Inv\_sa + Inv\_sb - Inv\_sa_{ref} - Inv\_sb_{ref})$$

$$K_2 = K_{2_{original}} + \frac{STK_2}{K_{stress\_vth0}^{LODK_2}} \cdot (Inv\_sa + Inv\_sb - Inv\_sa_{ref} - Inv\_sb_{ref})$$

$$ETA_0 = ETA_{0_{original}} + \frac{STETA_0}{K_{stress\_vth0}^{LOETA_0}} \cdot (Inv\_sa + Inv\_sb - Inv\_sa_{ref} - Inv\_sb_{ref})$$



# Stress Effect Model Verification

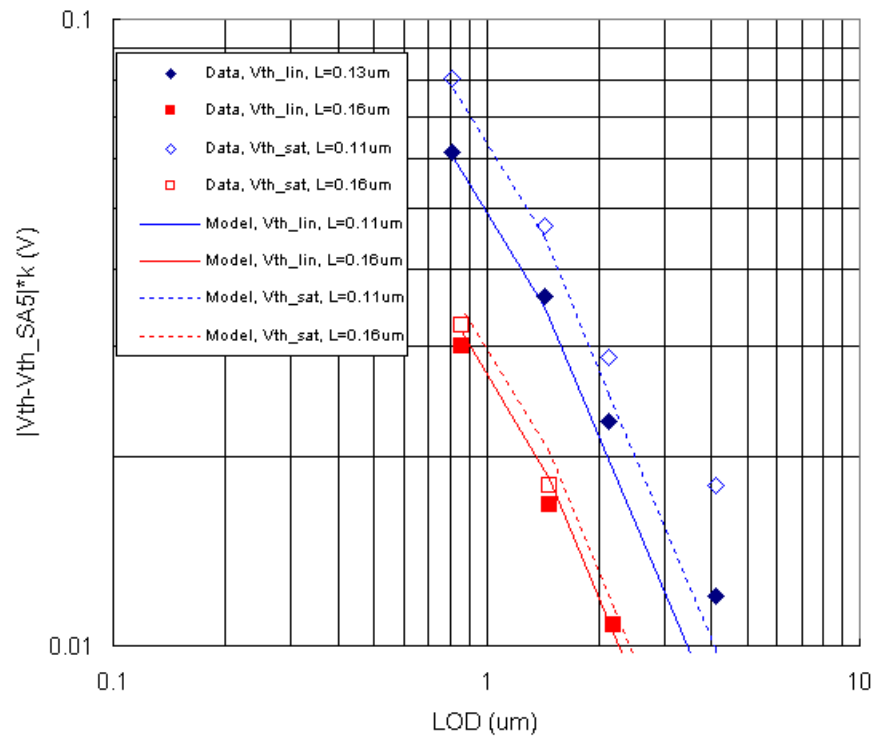




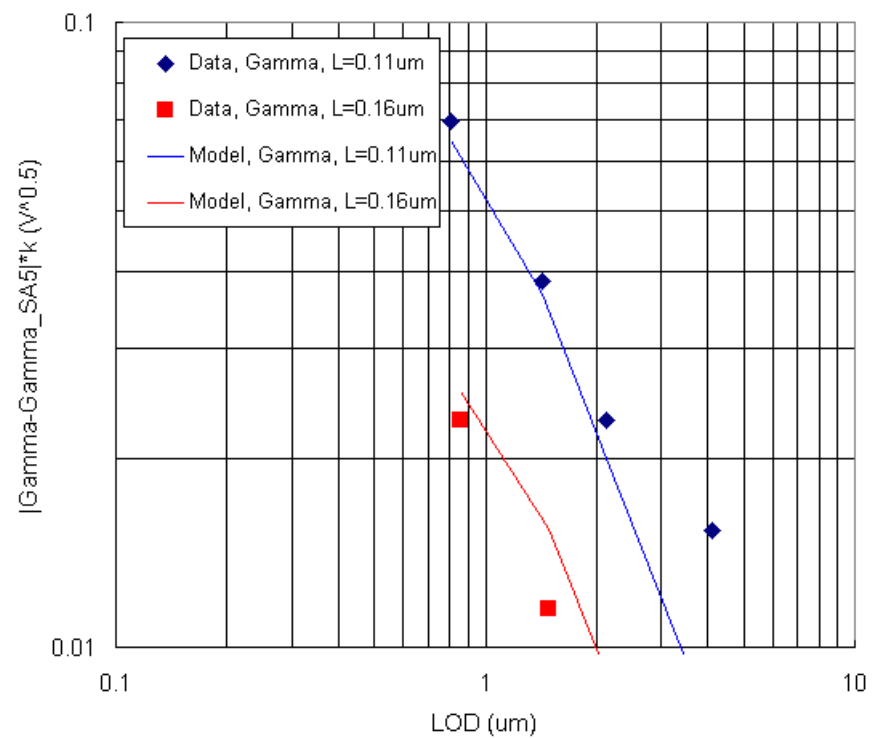


# Stress Effect Model Verification

NMOS, W=10um



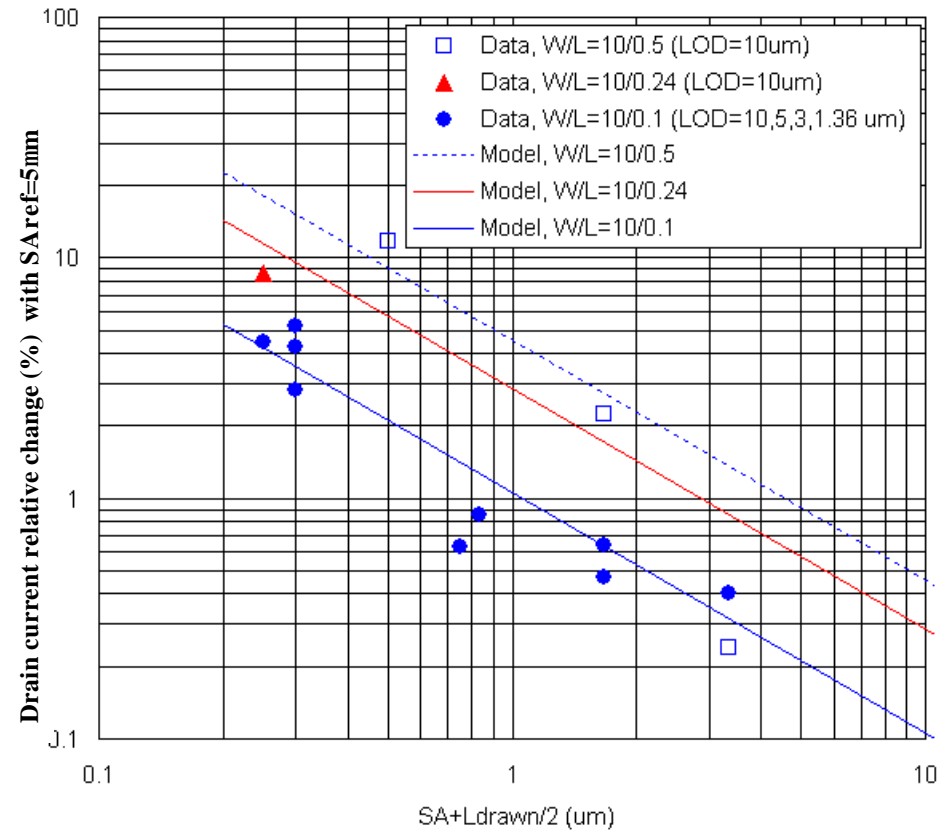
NMOS, W=10um





# Stress Effect Model Verification

NMOS, W=10um, SA≠SB





# Temperature Model Enhancement

Temperature mode **TEMPMOD** created:

- TEMPMOD = 0**: current model with VFB enhancement
- TEMPMOD = 1**: New format for vsat, prt, ua, ub, uc:

$$PARAM(T) = PARAM(TNOM) \cdot [1 + TEMP\_COEFF \cdot (T - TNOM)]$$



## Holistic Thermal Noise Model Enhancement

Refer to Chapter 9 of BSIM4 manual

$$q_{tnoi} = RNOIB \cdot \left[ 1 + TNOIB \cdot L_{eff} \cdot \left( \frac{V_{gsteff}}{E_{sat} L_{eff}} \right)^2 \right] \quad (9.2.5)$$

$$b_{tnoi} = RNOIA \cdot \left[ 1 + TNOIA \cdot L_{eff} \cdot \left( \frac{V_{gsteff}}{E_{sat} L_{eff}} \right)^2 \right] \quad (9.2.6)$$

Default RNOIA=0.577; RNOIB=0.37



## Unified Current Saturation -Velocity Overshoot Model

Price's approximation to HD model:

$$J = qn m E_y \left( 1 + \frac{l}{m E_y} \frac{\partial E_y}{\partial x} \right) + qD \frac{\partial n}{\partial x}$$

Approximate solution of Price's equation yields unified current expression that includes velocity saturation and velocity overshoot:

$$I_{DS,HD} = \frac{I_{DS0}}{1 + \frac{V_{dseff}}{L_{eff} E_{sat}^{OV}}}$$

where  $E_{sat}^{OV} = E_{sat} \left[ 1 + \frac{LAMBDA}{L_{eff} \cdot m_{eff}} \cdot \frac{\left( 1 + \frac{V_{ds} - V_{dseff}}{E_{sat} \cdot litl} \right)^2 - 1}{\left( 1 + \frac{V_{ds} - V_{dseff}}{E_{sat} \cdot litl} \right)^2 + 1} \right]$

$$I_{DS0} = I_{DS} (BSIM4.2.1) \cdot \left( 1 + \frac{V_{dseff}}{L_{eff} E_{sat}} \right)$$



## Unified Current Saturation: -Source-end Velocity Limit and Quasi-Ballistic Transport

HD transport source carrier velocity:

$$v_{sHD} = I_{DS,HD} / Wq_s$$

Ballistic transport source carrier velocity:

$$v_{sBT} = \frac{1-r}{1+r} VTL$$
$$r = \frac{L_{eff}}{XN \cdot L_{eff} + LC} \quad XN \geq 3.0$$

where VTL: thermal velocity,

Unified current expression with **velocity saturation, velocity overshoot and source velocity limit:**

$$I_{DS} = \frac{I_{DS,HD}}{\left[1 + \left(v_{sHD} / v_{sBT}\right)^{2MM}\right]^{1/2MM}}$$



# Direct Tunneling through Multiple-Layer Gate Stacks

❖ Gate Current modeled as  $J_G = Q_{INV} \cdot f_{IMP} \cdot T$

❖ For a single layer  $T \propto \exp(-\alpha t_{oxe})$

❖ For two layer case  $T \propto \exp(-a_{new} t_{oxe})$  where

$$a_{double} = a_1 \cdot f + a_2 \cdot (1-f) + f \cdot (1-f) \cdot \frac{V_{ox}}{3\hbar} \left( K_1 \cdot \sqrt{\frac{qm_1}{2f_{B1}}} - K_2 \cdot \sqrt{\frac{qm_2}{2f_{B2}}} \right)$$

$\alpha$  is the tunneling attenuation coefficient already modeled in BSIM4,  $f = Toxe1 / Toxe$

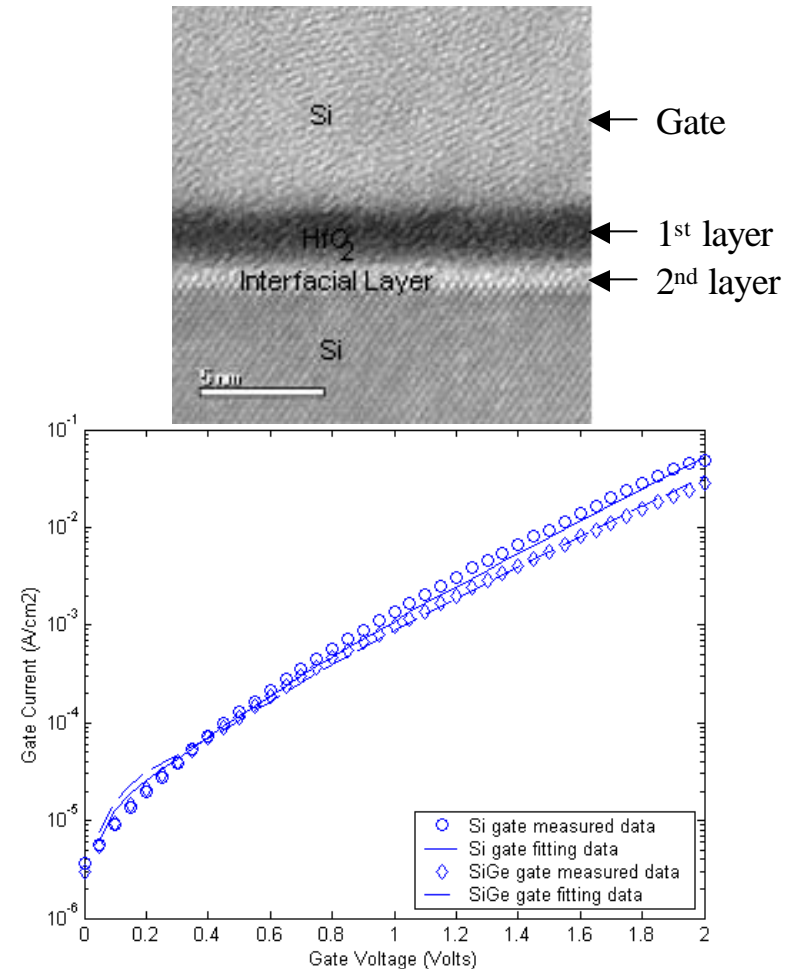
❖ Stands for multiple layers ( $N \geq 2$ ) as well.

❖ Using new tunneling attenuation coefficient and interpreted with tunneling equations in BSIM4, BSIM4 is now capable of modeling multi-layer gate tunneling.



# Verification

- ❖ Verified with data of existing gate stack of  $\text{HfO}_2$  and silicon oxynitride.
- ❖ Very good fit observed using BSIM model.
- ❖ BSIM4 direct tunneling equation thus models the multi-layer case.







## Forward Body Bias

To ensure a good model behavior of body effect, body bias is usually bounded between ( $V_{bsc}$ , and  $f_{s0}$  where  $f_{s0} = 0.95 f_s$ ). BSIM4.2.1 already has the smooth function for  $V_{bs}$  low bound. Following is the upper bound smooth function:

$$V_{bseff} = 0.95\Phi_s - 0.5 \left( 0.95\Phi_s - V'_{bseff} - d_1 + \sqrt{(0.95\Phi_s - V'_{bseff} - d_1)^2 + 4d_1 \cdot 0.95\Phi_s} \right)$$

**Where:**

$$V_{bseff} = V_{bc} + 0.5 \cdot \left[ (V_{bs} - V_{bc} - d_1) + \sqrt{(V_{bs} - V_{bc} - d_1)^2 - 4d_1 \cdot V_{bc}} \right]$$

Is the low bound smooth function.  $d_1 = 0.001V$ , and  $V_{bc}$  is the maximum allowable  $V_{bs}$  and found from  $dV_{th}/dV_{bs} = 0$  to be

$$V_{bc} = 0.9 \left( \Phi_s - \frac{K1^2}{4K2^2} \right)$$



## Gate Current Partition Bugfix

From Original:

$$I_{gcs} = I_{gc} \cdot \frac{PIGCD \cdot V_{ds} + \exp(-PIGCD \cdot V_{ds}) - 1 + 1.0e-4}{PIGCD^2 \cdot V_{ds}^2 + 2.0e-4}$$

and

$$I_{gcd} = I_{gc} \cdot \frac{1 - (PIGCD \cdot V_{ds} + 1) \cdot \exp(-PIGCD \cdot V_{ds}) + 1.0e-4}{PIGCD^2 \cdot V_{ds}^2 + 2.0e-4}$$

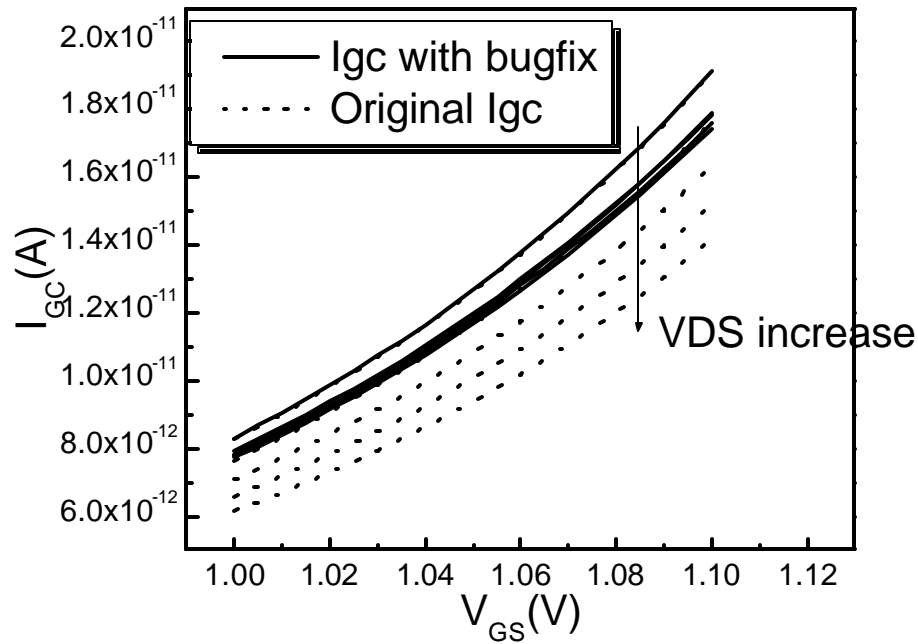
To:

$$I_{gcs} = I_{gc} \cdot \frac{PIGCD \cdot V_{dseff} + \exp(-PIGCD \cdot V_{dseff}) - 1 + 1.0e-4}{PIGCD^2 \cdot V_{dseff}^2 + 2.0e-4}$$

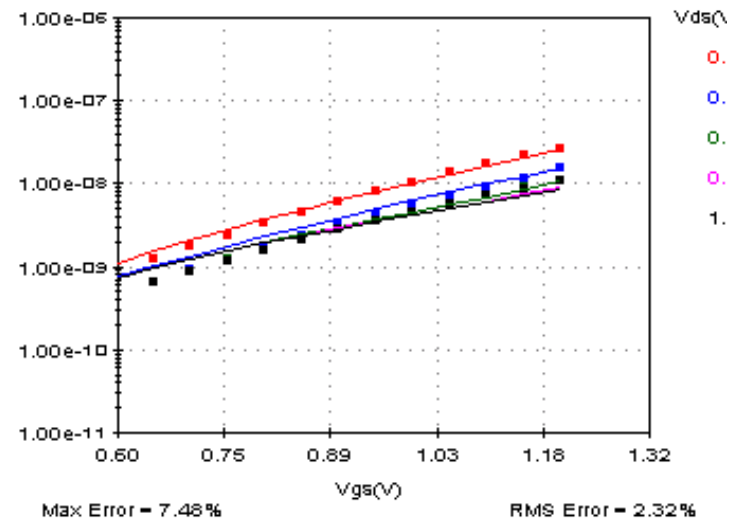
$$I_{gcd} = I_{gc} \cdot \frac{1 - (PIGCD \cdot V_{dseff} + 1) \cdot \exp(-PIGCD \cdot V_{dseff}) + 1.0e-4}{PIGCD^2 \cdot V_{dseff}^2 + 2.0e-4}$$



# Gate Current Partition Bugfix



Effect of gate current bug fix



Comparison with experimental data



## New Parameters in BSIM4.3.0

### -Stress Effect

Parameter Name	Description	Default Value	Binnable?	Note
SA	<b>INSTANCE</b> parameter: Distance between OD edge to Poly from one side	0.0		If not given or ( $\leq 0.0$ ), stress effect will be turned off
SB	<b>INSTANCE</b> parameter: Distance between OD edge to Poly from the other side	0.0		If not given or ( $\leq 0.0$ ), stress effect will be turned off
SD	<b>INSTANCE</b> parameter: Distance between neighbour fingers	0.0		for NF >1: if not given or ( $\leq 0.0$ ), stress effect will be turned off
saref	Reference distance between OD edge to poly of one side	1.E-06[m]	no	>0.0
sbref	Reference distance between OD edge to poly of the other side	1.E-06[m]	no	>0.0
wlod	Width parameter for stress effect	0.0 [m]	no	
ku0	Mobility degradation/enhancement coefficient for stress effect	0.0 [m]	no	
kvsat	Saturation velocity degradation/enhancement parameter for stress effect	0.0[m]	no	$-1 \leq kvsat \leq 1$
tku0	Temperature coefficient of ku0	0.0	no	
lku0	Length dependence of ku0	0.0 [m <sup>llo<sub>d</sub>ku0</sup> ]	no	



## New Parameters in BSIM4.3.0 -Stress Effect

Parameter Name	Description	Default Value	Binnable ?	Note
wku0	Width dependence of ku0	0.0 [m <sup>wlodku0</sup> ]	no	
pku0	Cross-term dependence of ku0	0.0[m <sup>llodku0+wlodku0</sup> ]	no	
llodku0	Length parameter for u0 stress effect	0.0	no	>0
wlodku0	Width parameter for u0 stress effect	0.0	no	>0
kvth0	Threshold shift parameter for stress effect	0.0[V*m]	no	
lkvth0	Length dependence of kvth0	0.0[V*m <sup>llodku0</sup> ]	no	
wkvth0	Width dependence of kvth0	0.0[V*m <sup>wlodku0</sup> ]	no	
pkvth0	Cross-term dependence of kvth0	0.0[V*m <sup>llodku0+wlodku0</sup> ]	no	
llodvth	Length parameter for Vth stress effect	0.0	no	>0
wlodvth	Width parameter for Vth stress effect	0.0	no	>0
stk2	K2 shift factor related to Vth0 change	0.0[m]	no	
lodk2	K2 shift modification factor for stress effect	1.0	no	>0
steta0	eta0 shift factor related to Vth0 change	0.0[m]	no	
lodeta0	eta0 shift modification factor for stress effect	1.0	no	>0



## New Model Parameters in BSIM4.3.0

### -Unified Current Saturation

Parameter Name	Description	Default Value	Binnable ?	Note
LAMBDA	Velocity overshoot coefficient	0.0	yes	If not given or ( $\leq 0.0$ ), velocity overshoot will be turned off
VTL	Thermal velocity	2.0e5 [m/s]	yes	If not given or ( $\leq 0.0$ ), source end thermal velocity limit will be turned off
LC	Velocity back scattering coefficient	0.0[m]	no	$\sim 5e-9$ (m) at room temperature
XN	Velocity back scattering coefficient	3.0	yes	

### Temperature Model

TEMPMOD	Temperature mode selector	0	no	If=0, original model will be used If=1, new format will be used
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### Holistic Thermal Noise

RNOIA	Thermal noise coefficient	0.577	no	
RNOIB	Thermal noise coefficient	0.37	no	